

NeoGrowth Silicon:

Low oxygen, high purity, proven crystal growth method for 450mm + silicon optics

Developed at SolarWorld Americas

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Plan



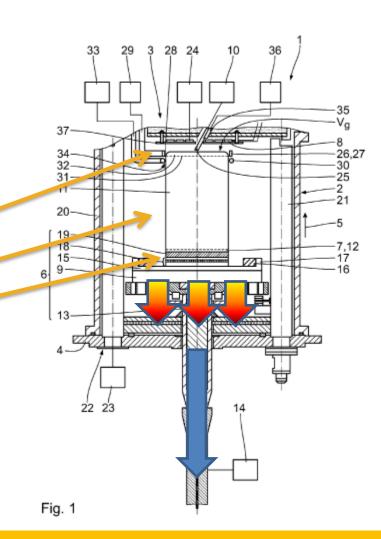
- Introduce NeoGrowth crystal growth
 - Principles of operation
 - Distinctions relative to other methods
- Properties of NeoGrowth silicon
 - Dislocations
 - Impurities and lifetime
 - Doping

NeoGrowth Silicon: What is it?



US 9,315,917 B2

- Basics: most similar to pedestal growth
 - Continuous, Float Zone like process with balanced input and freezing of liquid
 - Non-contact solidification: no containing crucible
 - Large area seeding process with a seed having a cross-section close to that of the finished ingot
 - Capable of extremely low thermal stresses even at high growth speed
 - Capable of producing circular or squarish crosssections
- Stoddard et al, Progress in Photovoltaics, 1/2018
- Stoddard et al, Journal of Crystal Growth vol 452



U.S. Patent

Apr. 19, 2016

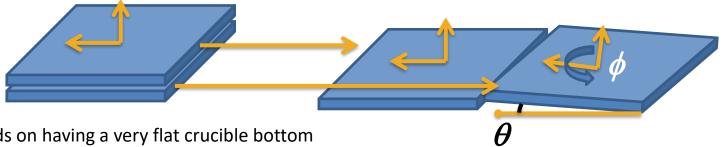
Sheet 1 of 9

CM-Si Challenges: Seeding

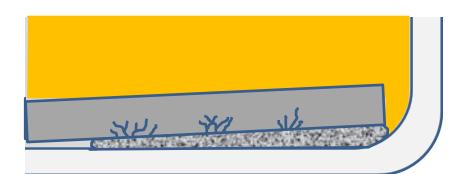


Seed boundaries

- Angle mismatch of >0.1 degrees can lead to sub-grain boundary
- Two seeds cut to square from the same block can meet this requirement for ϕ



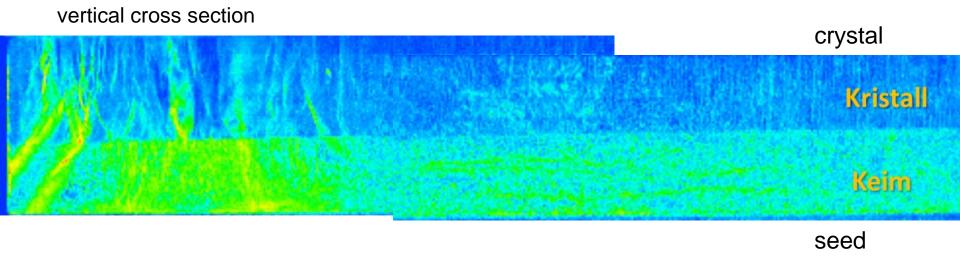
- θ depends on having a very flat crucible bottom
 - small chips, coating variations, crucible bumps and corners can cause problems
- Liquid silicon undercutting also causes significant problems
 - The liquid can come down the edges or between seeds
 - As it pushes in, it is cooled and solidifies
 - Expansion on solidification causes stress
 - Heavy dislocations in seed
 - Lifts and misaligns seeds, creating small angle GB's between seeds



CM difficulties: crucible and coating



- The crucible is an unavoidable source of impurites
 - Dissolved oxygen, nitrogen, metals
 - Nitride particles



- Uneven support of the seeds and weight loading of heavy feedstock cause seed dislocations
 - Good news: most do not propagate
 - Bad news: many still do

Traditional Mono challenges



Czochralski Growth

- High oxygen concentration (15-25 ppma)
- Small cross-section
- Batch doping limitations
- Long times for seed-in, stabilization, tail
- That Czech name

Float Zone

- Feedstock limitations (high density polysilicon rods)
- Diameter limitations (200 mm max)
- High Frequency Inductive heater
- So how about some details on NeoGrowth?

NeoGrowth melt supply

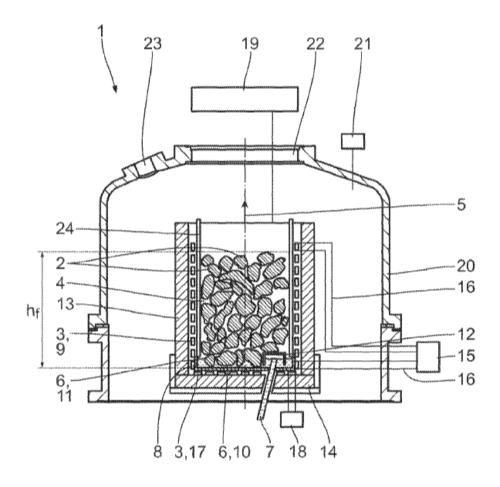


Requirements for melt supply

- Mass flow must match crystal growth rate in order to prevent build up or diminishing of melt puddle height
- Smooth flow preferred to avoid melt vibrations
- Through-flow of unmelted bits of feedstock material must be avoided

Nice to have

- Feedstock flexibility
- Reusability over multiple runs
- Minimal liquid contact with foreign material

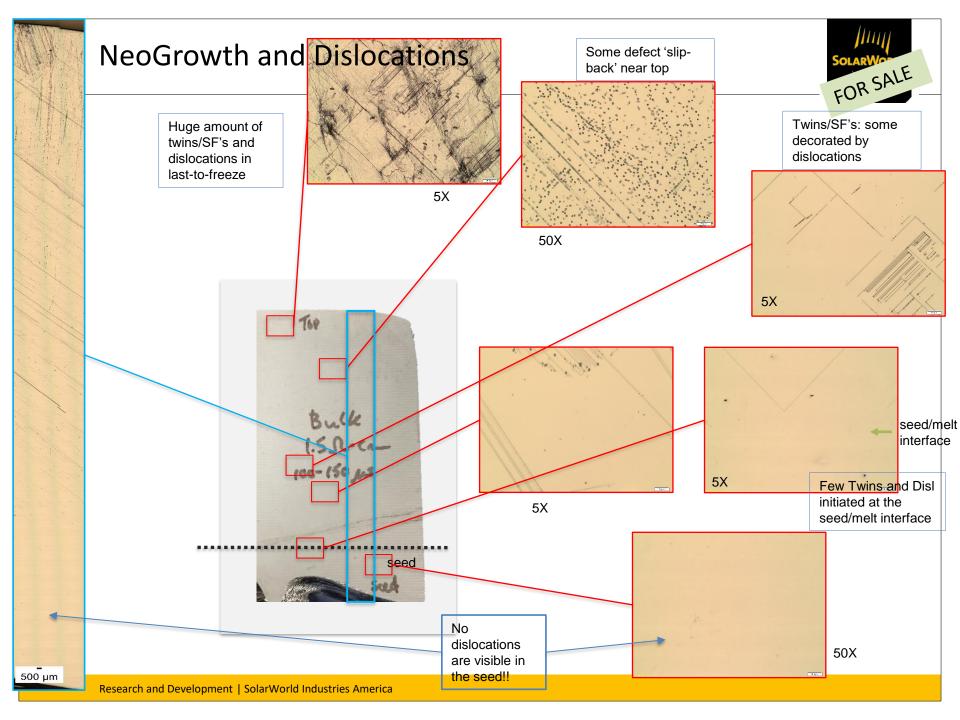


NeoGrowth Properties



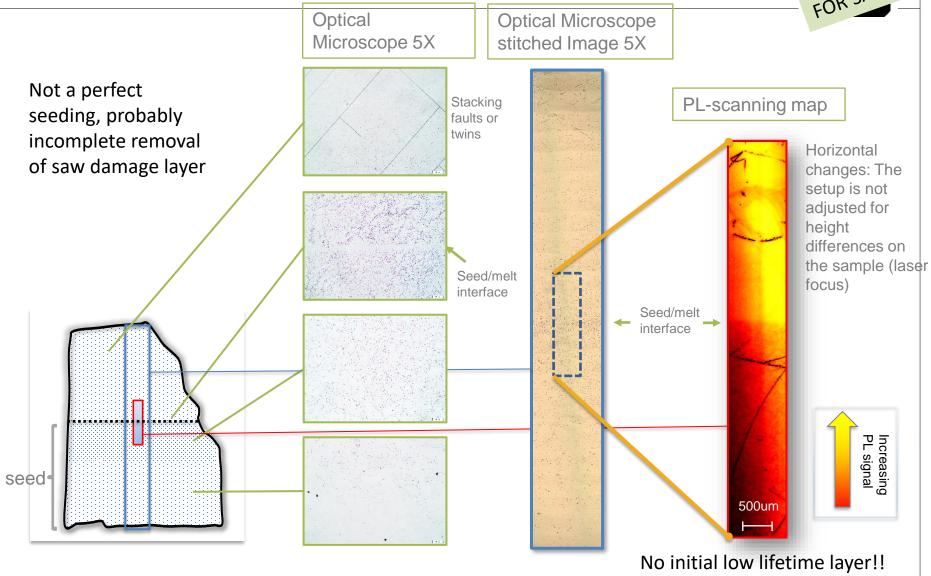
- We have grown crystals at 230mm, 300mm and 450mm diameter in square and circular cross-sections
- Dislocations present from seeding do not cause structure loss
 - Maintaining low thermal stress during growth prevents the evolution into dislocation clusters and small-angle grain boundaries
- We have not yet been able to grow a dislocationfree crystal, but that has not been a main goal
- We have found a tendency for twins to form at the nodes of the crystal unless great care is taken
- Height
- Growth rate





NeoGrowth seeding interface

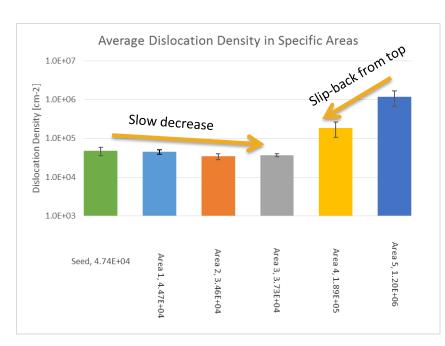


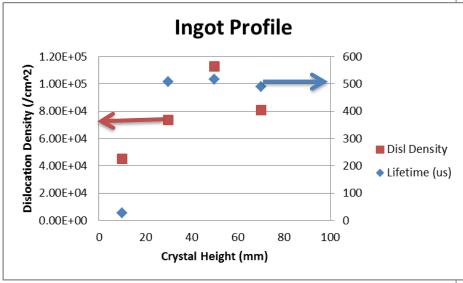


Dislocation evolution



- Cool-down stress can change things, but we often see a slow decrease in dislocation density as ingot growth proceeds (left, typical)
- Up to low 10⁵ disl/cm², we see no significant correlation of dislocation density and MCL

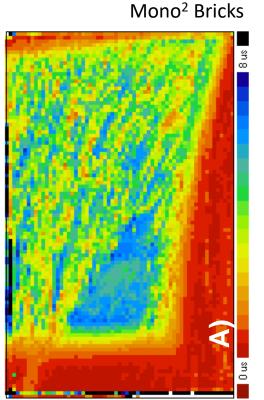


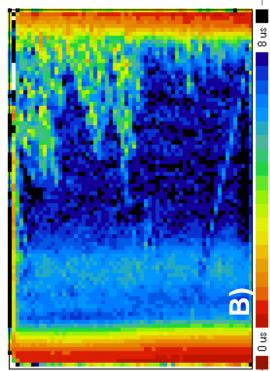


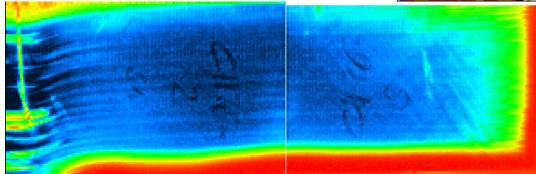
A word about dislocation cascades



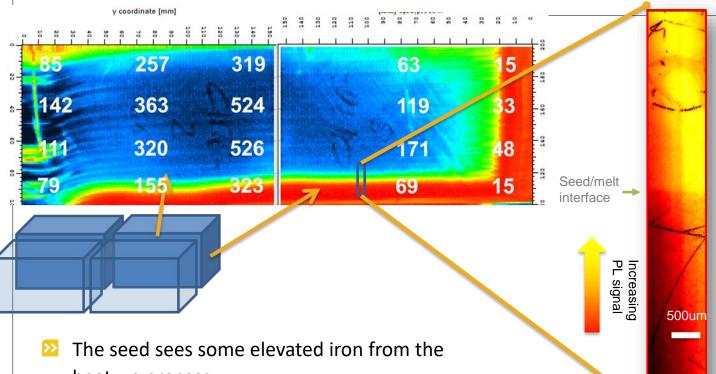
- One of the biggest limitations of the Mono² / quasi-mono process is the presence of dislocation cascades
 - Generated at seed tile boundaries
 - Generated higher from inclusions and built-up stress
- NeoGrowth has no seed tile boundaries
- NeoGrowth has no inclusions
- NeoGrowth has very low simulated stress even at >50 cm (< 5MPa)</p>







Impurities



- heat-up process
- The grown material has exceedingly high purity
- The exterior of the ingot sees some post-growth iron deposition from the hot zone ambient
 - Hot zone material quality is crucial
- Minority carrier lifetime post diffusion measured as high as 1.7 ms at 1.5 ohm-cm

Quasi-mono: Iron contamination at seed interface NeoGrowth: No iron contamination

at seed interface

FOR SALE

The Light Elements



- Oxygen source in melter apparatus, but good argon sweeping keeps levels low
- The only carbon source is gaseous:
 - SiO + C -> SiC + CO
 - Carbon is controlled through the atmospheric conditioning

FTIR Concentrations (atoms/cm³)

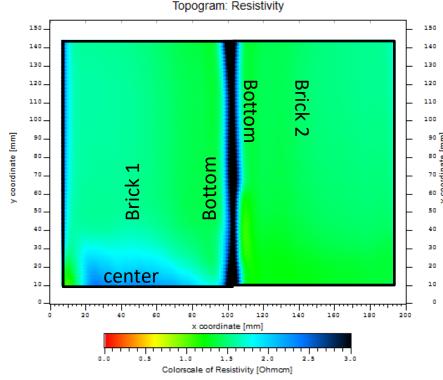
[O _i]	Center	Half-way	Edge
Тор	4.00E+17	3.73E+17	3.87E+17
Middle	5.05E+17	3.88E+17	3.47E+17
Bottom	5.73E+17	4.85E+17	4.18E+17
[C _s]	Center	Half-way	Edge
Тор	9.43E+16	1.65E+17	9.76E+16
Middle	7.80E+16	9.55E+16	1.27E+16
Bottom	7.11E+16	3.27E+16	< 1E+16

Doping



- Doping does not follow Scheil's equation because there is a constant supply of fresh feedstock
- Low segregation coefficient dopants perform well: dope once at the beginning and slowly deplete the melt concentration
- Evaporation can be an issue, depending on the ambient pressure
- Zone height variations will also change the doping by changing the melt concentration

$$C(x) = C_0 * k * e^{-krxA/V}$$

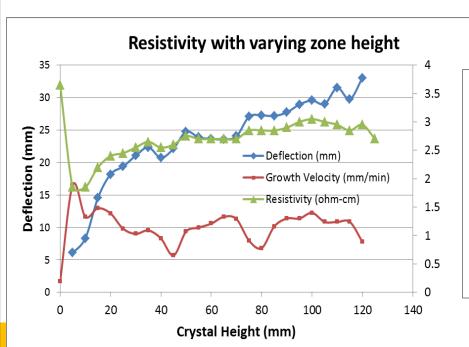


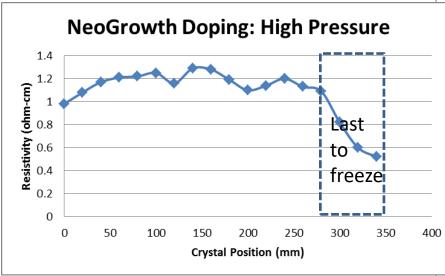
- k is the segregation coefficient
- $r = \rho_s/\rho_l$ is the ratio of densities
- x is the linear crystal position
- A is the cross-section of crystal growth
- V is the liquid volume Or A/V = 1/h where h is the zone height

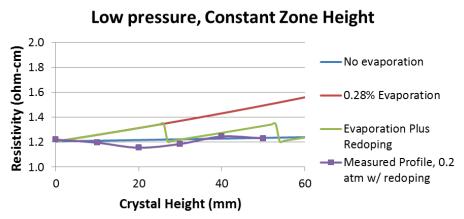
Doping



- Ambient pressure has a big effect on dopant evaporation
 - High pressure: dope once and done
 - Low pressure: have to redope
- Zone height also has a significant effect







Challenges



Early Challenges Overcome

- Stability of melt puddle
- Uniformity of melt flow
- Argon purge design for low carbon

Current challenges

- Maintaining low stress to avoid dislocation multiplication narrows the process window
- Twins coming from the nodes are pernicious
 - Problem solved at 230 mm, but not fully resolved at 450 mm

Opportunities

- Dislocation-free seeding seems possible, but not yet repeatable
- Potential to increase the process stability via melt edge contact

Conclusions



- NeoGrowth method demonstrated to have good promise for solar substrates
 - Low dislocations, oxygen, metals
 - High throughput drives low cost
 - Good doping and high lifetime
 - Possible extension to dislocation-free technique
 - Technique and equipment are part of the sale of SolarWorld Americas
- Excellent crystal growth advice now available from The Stoddard Consultancy

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Questions?



